

1762



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Inventors: Wei Pan, David Russell Evans and
Sheng Teng Hsu

Serial No: 09/978,434

Filed: October 16, 2001

Title: METHOD OF CONTROLLING
THE INITIAL GROWTH OF CVD
COPPER FILMS BY SURFACE
TREATMENT OF BARRIER
METALS FILMS

PATENT APPLICATION

Attorney Docket No.
SLA0499

Group Art Unit: 1762

Examiner:

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CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this correspondence is being deposited
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Signature Date: 3/5/02

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**TRANSMITTAL OF SUPPLEMENTAL
DECLARATION UNDER 37 C.F.R. §1.67(a)**

Hon. Commissioner for Patents
Washington, D.C. 20231

Sir:

This correspondence transmits an accompanying Supplemental
Declaration in the above-identified patent application. The Supplemental
Declaration includes language inadvertently omitted from the originally-filed

Declaration stating that the person making the declaration has reviewed and understands the contents of the specification, including the claims, as amended by any amendment specifically referred to in the declaration, and acknowledges the duty to disclose information which is material to the examination of the application in accordance with 37 C.F.R. §1.56.

Please enter this Supplemental Declaration in the application file.

The Commissioner is hereby authorized to charge any fees associated with this communication to Deposit Account No. 19-1457. A duplicate copy of this authorization is enclosed.

Date: _____

3/5/02

Respectfully submitted,

By: _____

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